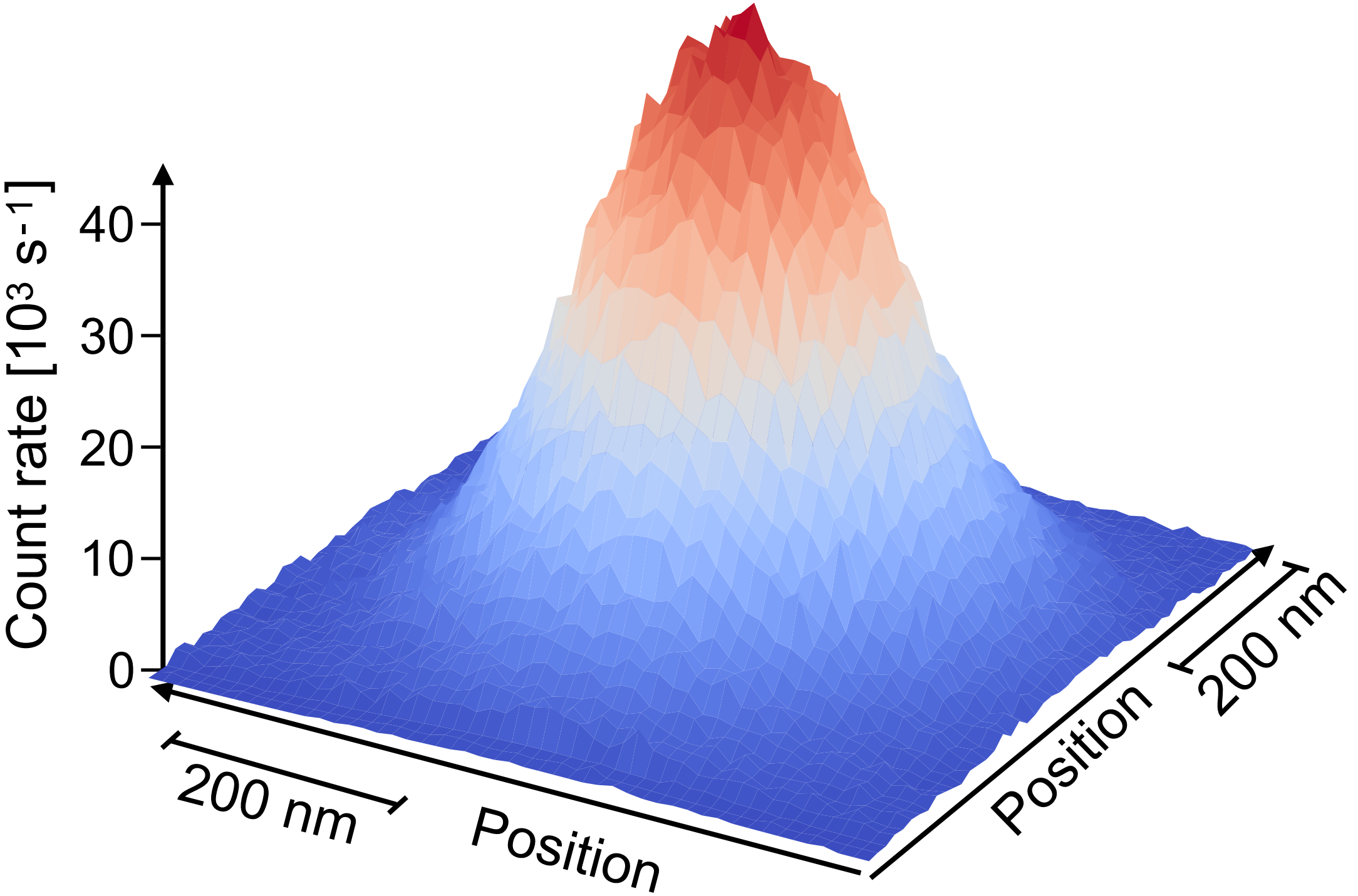
Count rate [10³ s⁻¹]
40
30
20
10
0
200 nm
Position
Position
200 nm